

A Laser-Driven Light Source (LDLS) as a portable spectral irradiance calibration source in the UV range and other radiometric applications.

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Before we start.....

- VSL is the **National Metrology Institute** of the Netherlands, appointed by the Dutch government to maintain and develop the national measurement standards.
- **Knowledge institute** in the field of metrology.
- We also provide **metrology services** to customers
- Only one location (Delft)

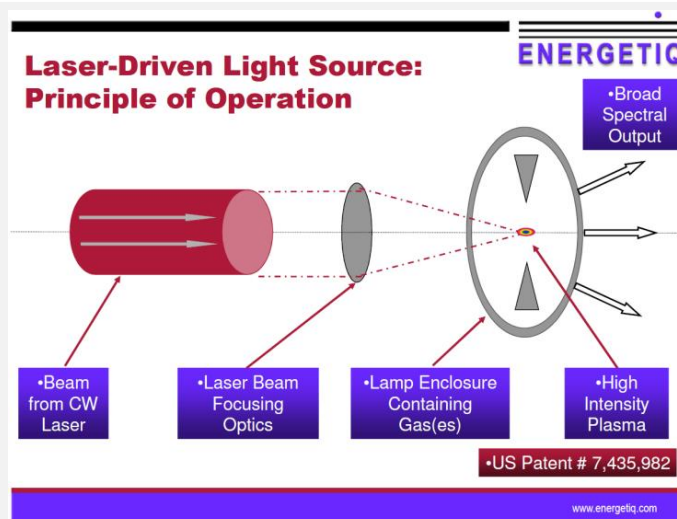


Outline

- General overview on a LDLS source
- Potential as spectral irradiance calibration source: pro and cons
- A practical example: calibration of an array spectroradiometer
- Some other special applications: wavelength calibration
- Conclusions

General overview of a Laser Driven Light Source (LDLS)

EQ-99 LDLS™ System



Warm-up time about 60 minutes to get excellent temporal stability (few ppm)
Irradiance level without collimation not very high but very flat when compared to a 1000 W FEL.

Need for nitrogen purging for high throughput in the short UV range.

Long term stability: ?? (operated for \approx 600 hours so far)

Why interested in new sources for UV?

If we want to measure $E(\lambda)$ with a detector having a respons. $R_{\lambda^*}(\lambda)$

$$S_{\lambda^*} = \int E(\lambda) R_{\lambda^*}(\lambda) d\lambda$$

$$\text{SNR} = \frac{S_{\lambda^*} - S_{\text{dark}}}{\sqrt{\sigma^2(S_{\lambda^*}) + \sigma^2(S_{\text{dark}})}}$$

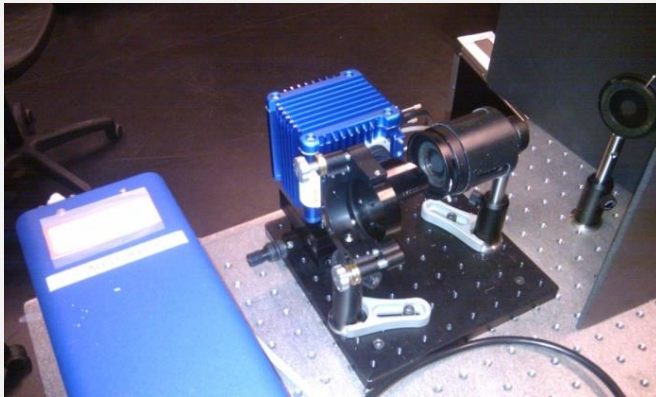
If the final goal uncertainty is u (%) then one has to have, as a rule of thumb,

$$\text{SNR} > \frac{3}{u}$$

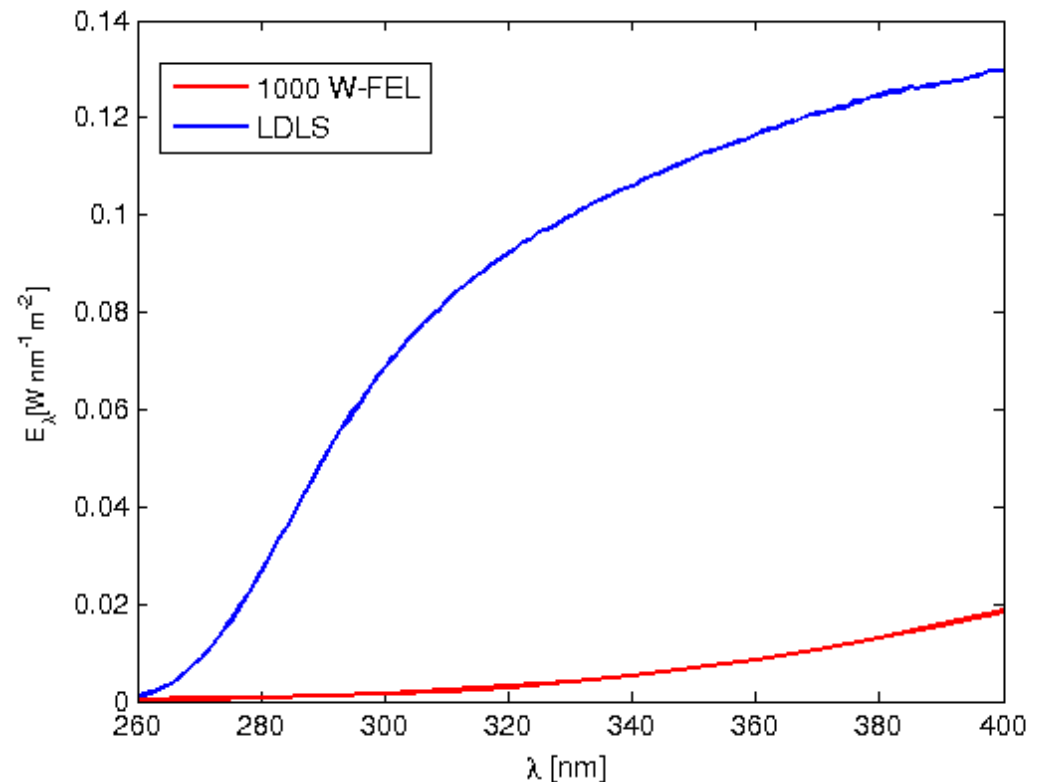
Ex. $u = 1\%$
 $\text{SNR} > 300$

Spectral irradiance standard

At 50 cm distance, non collimated beam, irr. far below $0.003 \text{ W}/(\text{m}^2 \text{ nm})$



The collimated LDLS gives higher spectral irradiance levels, but...



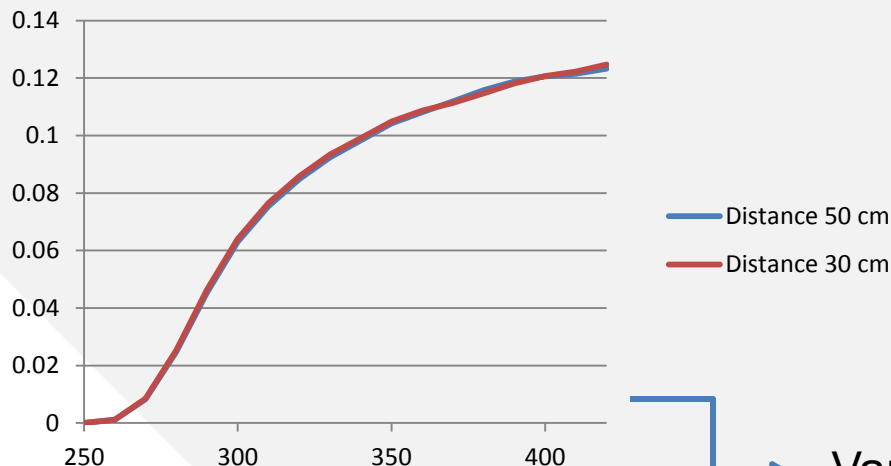
Beam profile: sensitivity in longitudinal and lateral positioning

Estimated positioning sensitivities
(measured at three wavelengths, 280nm,
340nm and 400nm)

$S_x \approx 2\%/mm$

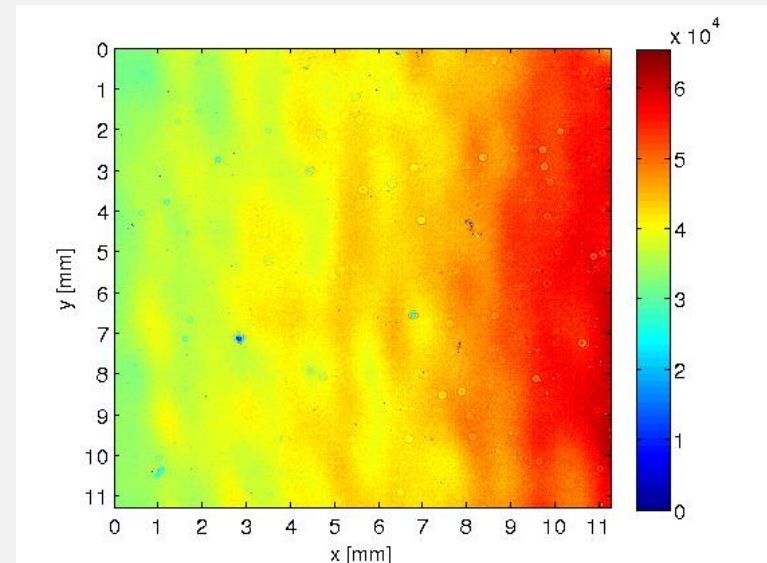
$S_y \approx 0.5\%/mm$

$S_z \approx 0.012\%/mm$



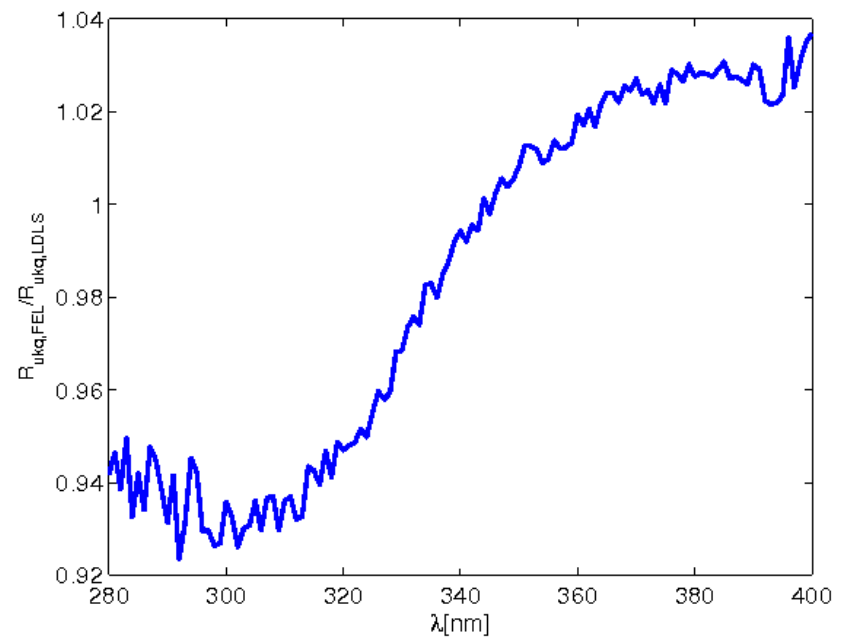
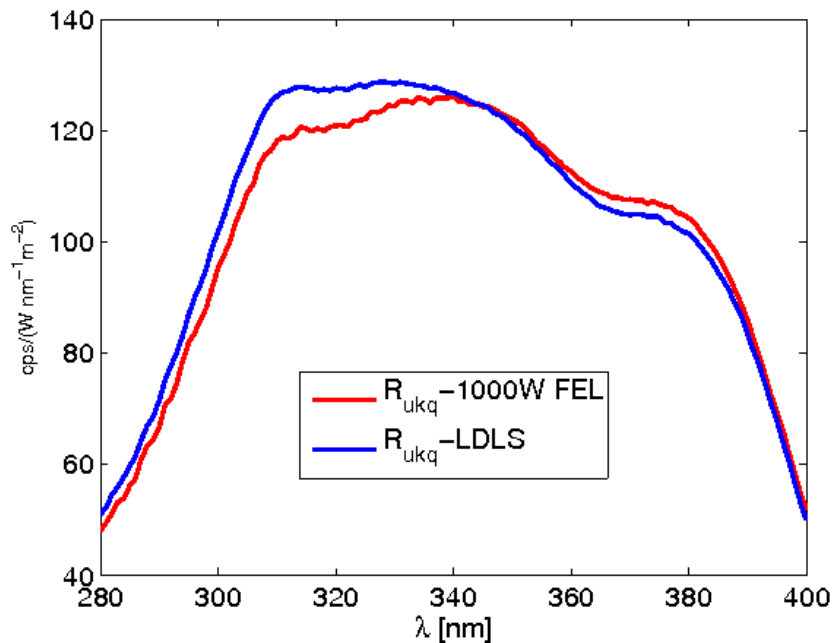
Variation along z is negligible
for most applications

Spectrally integrated profile



Determination of the responsivity of an array spectrometer: UKQ

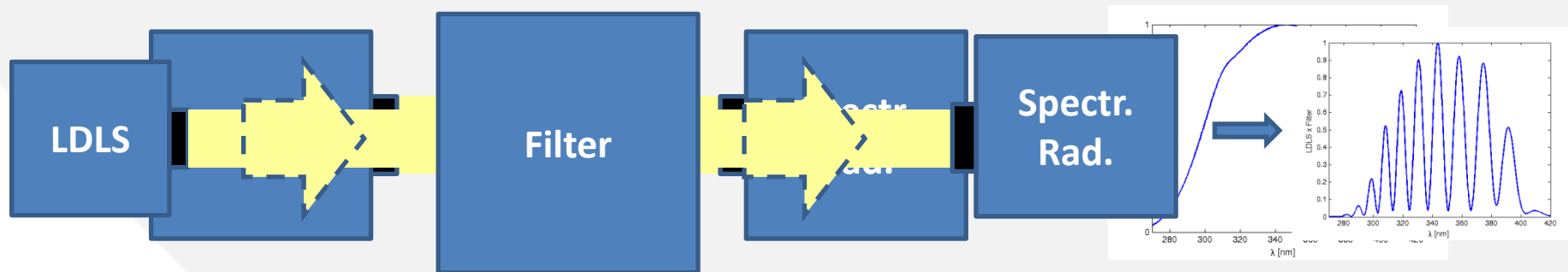
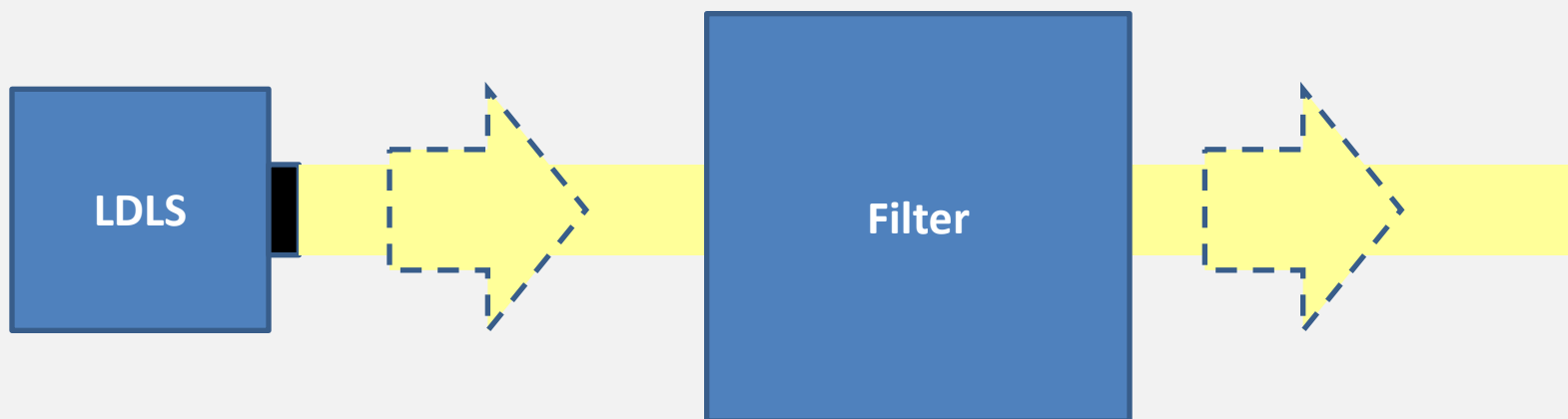
Ocean Optics array spectrometer, (230-410)nm, 50 μm slit, cooled.
Entrance optics a 2' averaging sphere, $\frac{1}{2}'$ input port, fiber coupled.



Application # 2: wavelength calibration

Goal: realization of a portable wavelength calibration system in the UV

The collimated source, coupled to a proper filter, can be part of an accurate wavelength calibration tool



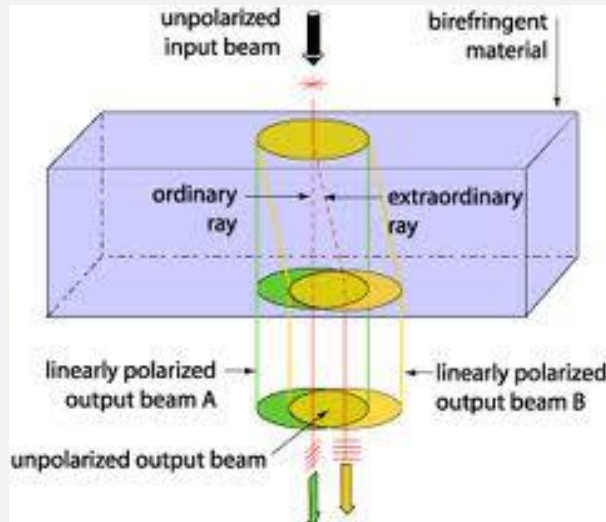
Birefringence-based filter

Birefringence:

A material shows different refractive indices for different polarization states

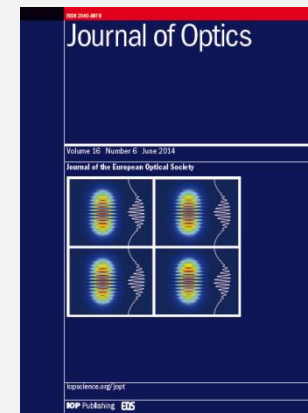


Anisotropic medium



It can be used for many different goals in metrology.

R. Koops *et al* 2014 *J. Opt.* **16** 065701

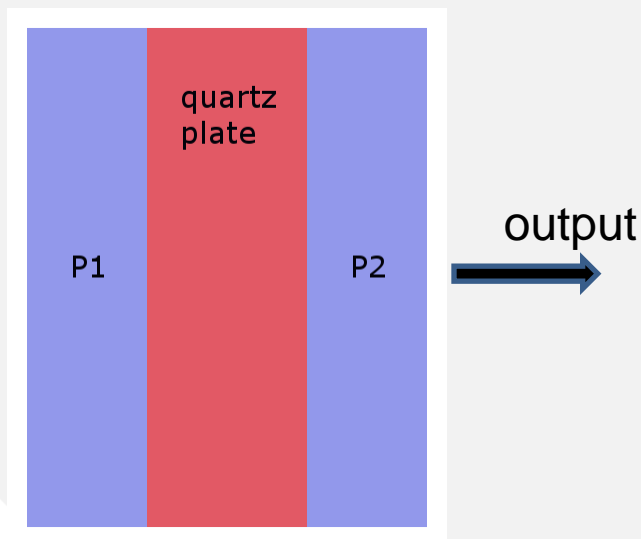


Birefringence-based UV wavelength ruler

Requirements:

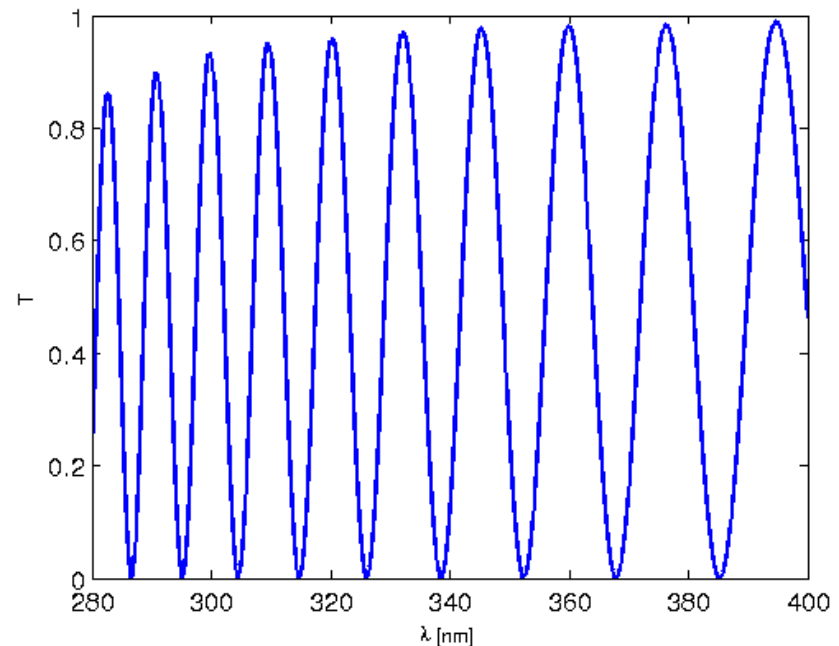
- Spectral range 280nm-400nm
- Temperature variations should be controlled within at least 0.1 C°.
- We need enough intense lines, but not too narrow (FWHM~10-20nm)

One/-stage Lyot filter

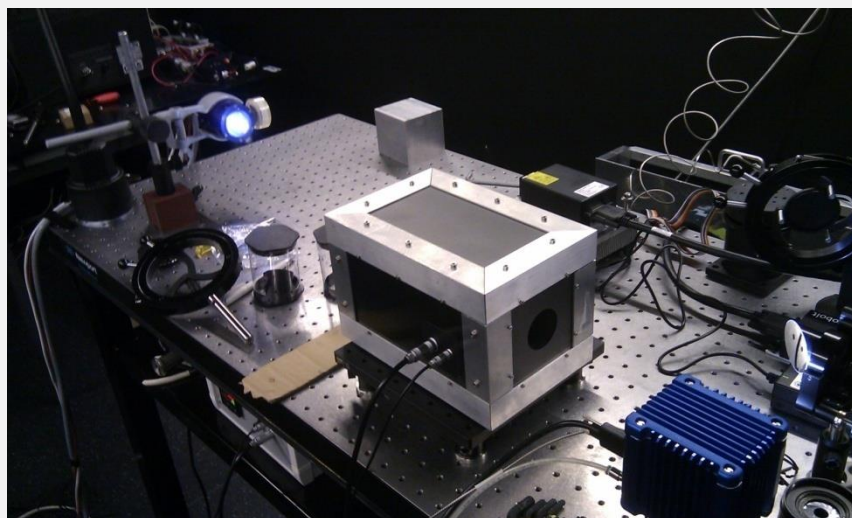
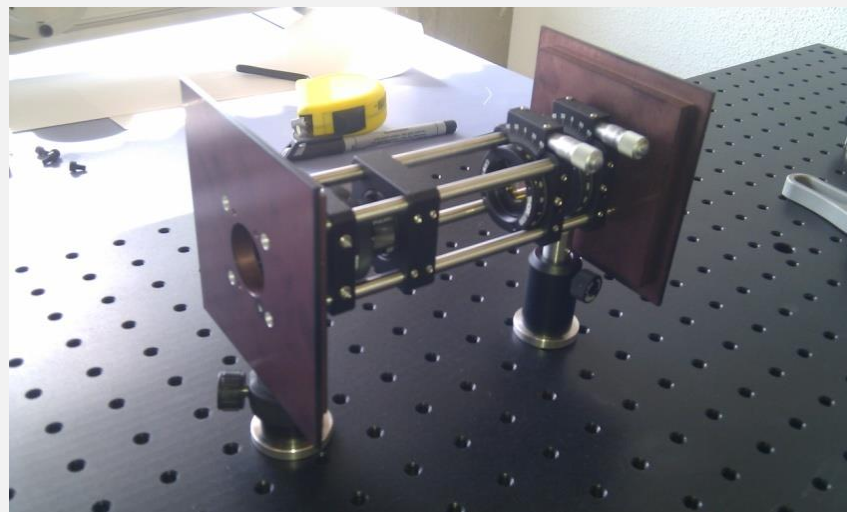
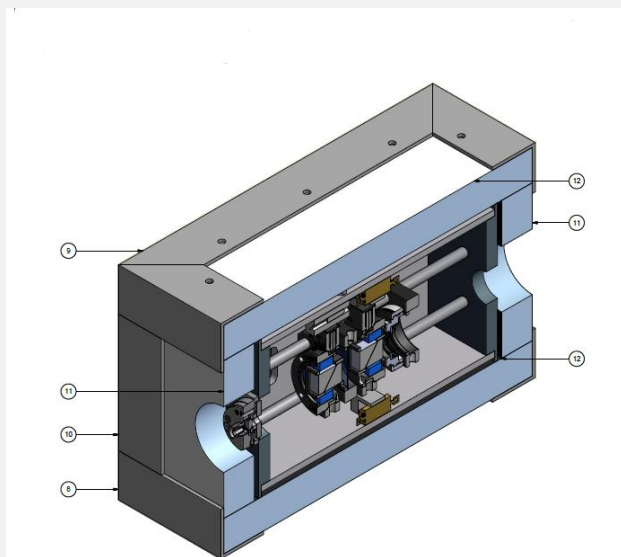


Simulations.

Nominal thickness quartz plate of 0.7mm+0.02mm



Design and implementation of a on-field calibration unit



Method for data analysis

How to solve the inverse problem?

First we choose a merit function to minimize:

$$\chi^2 = \frac{1}{N} \sum_{i=1}^N \left[\frac{I_i^{(m)} - I(\mathbf{p}_i, \mathbf{a})}{\sigma_i} \right]^2,$$

The parameters \mathbf{a} are adjusted in order to minimize the distance between measurements and simulations

While the uncertainty is estimated through:

$$\Delta a_j = 3\sqrt{C_{jj}},$$

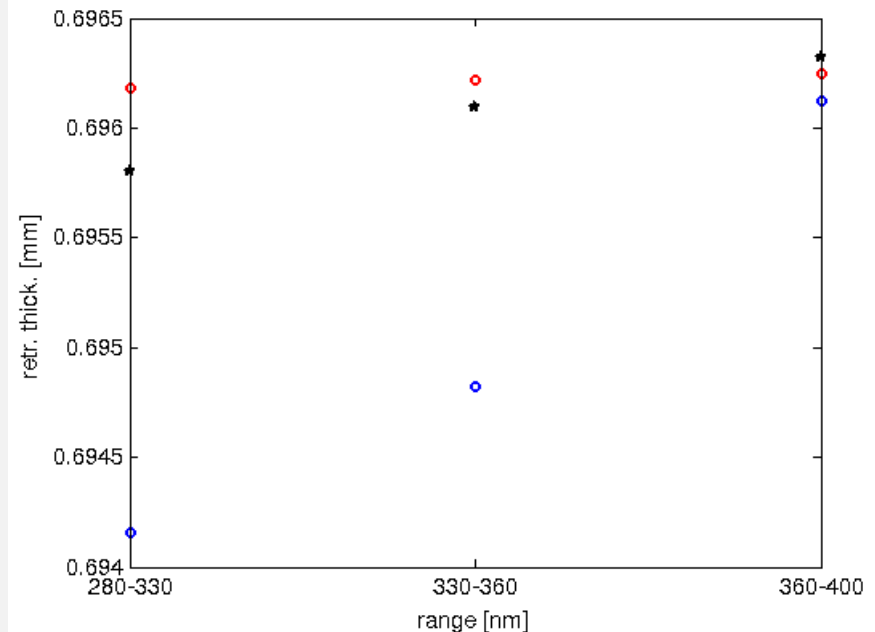
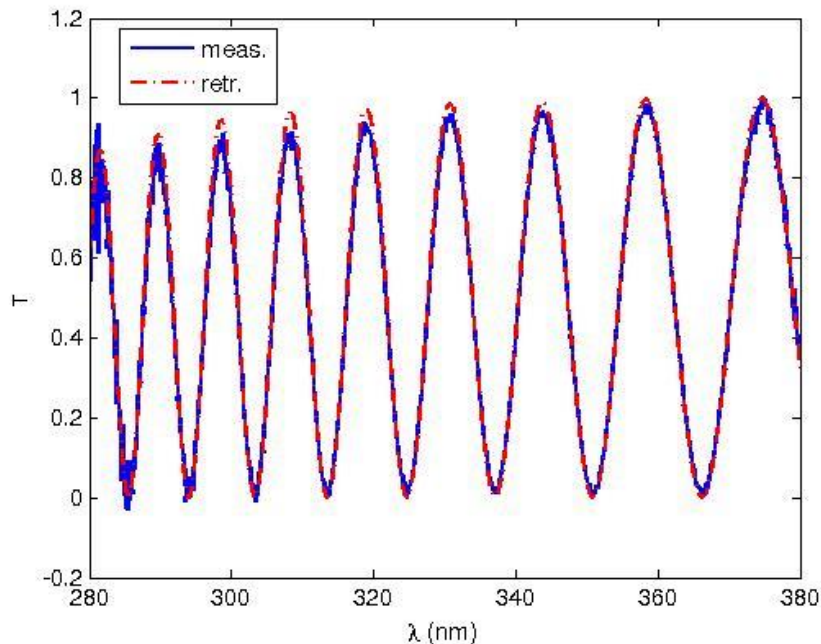
where

$$[C_{jk}] = [\alpha_{jk}]^{-1}$$

$$[\alpha_{jk}] = \frac{1}{2} \frac{\partial^2 \chi^2}{\partial a_k \partial a_l} = \frac{1}{N} \sum_{i=1}^N \frac{1}{\sigma_i^2} \left[\frac{\partial I(\mathbf{p}_i, \mathbf{a})}{\partial a_j} \frac{\partial I(\mathbf{p}_i, \mathbf{a})}{\partial a_k} \right]_{\mathbf{a}=\mathbf{a}_{\min}}$$

Ideal vs actual transmission

Hence, we need a parametrized forward model which is fed into a Levenberg-Marquardt algorithm



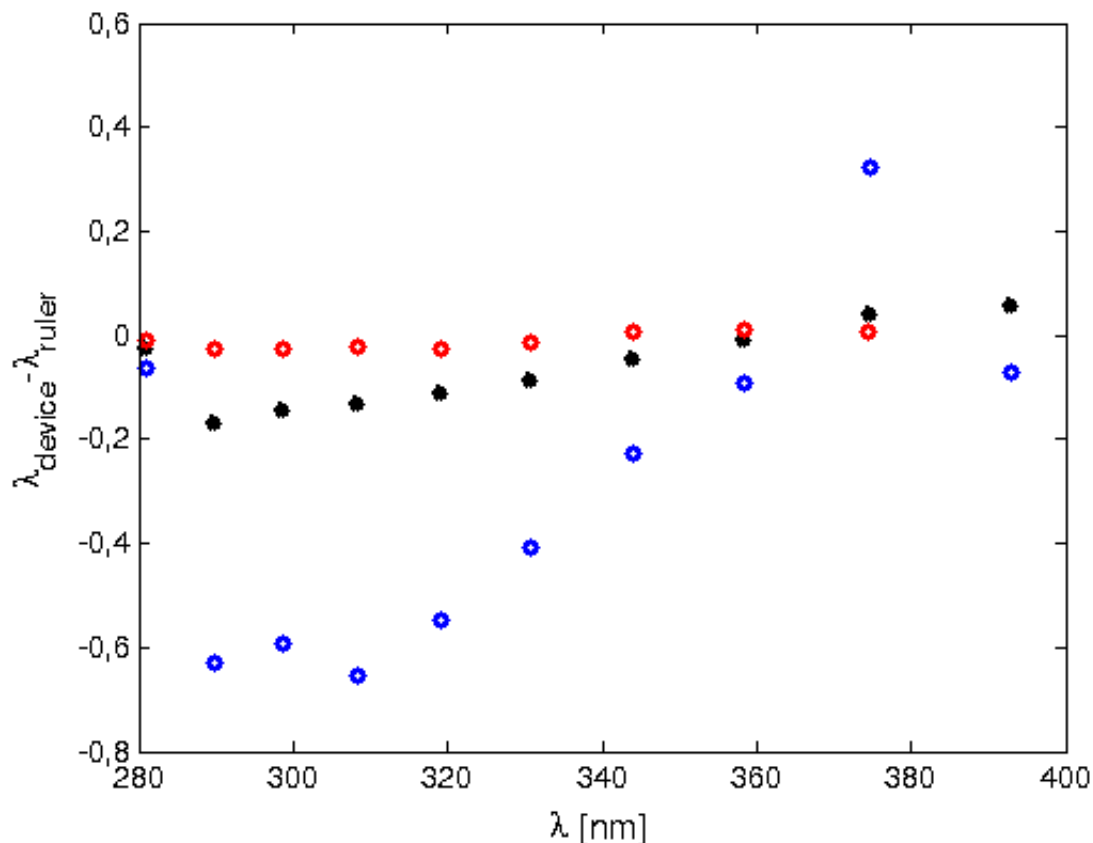
From a set of calibrated instruments (in a limited spectral region) the actual thickness is retrieved off-line

Retrieved thickness

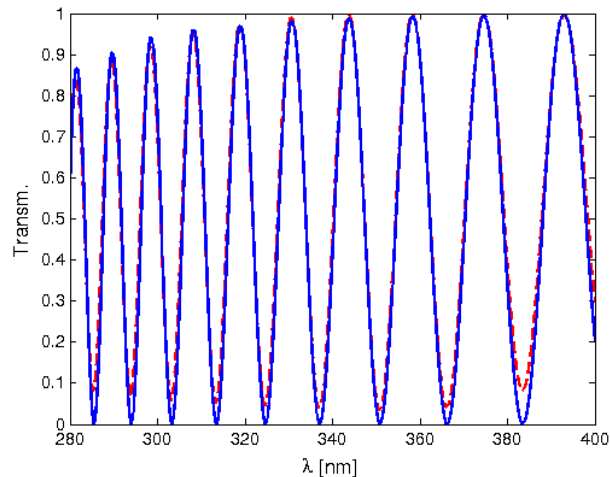
$d = 0.6962 \text{ mm}$
 $U(k=2) = 40 \text{ nm}$

With this value we can
 generate the wavelength
 scale

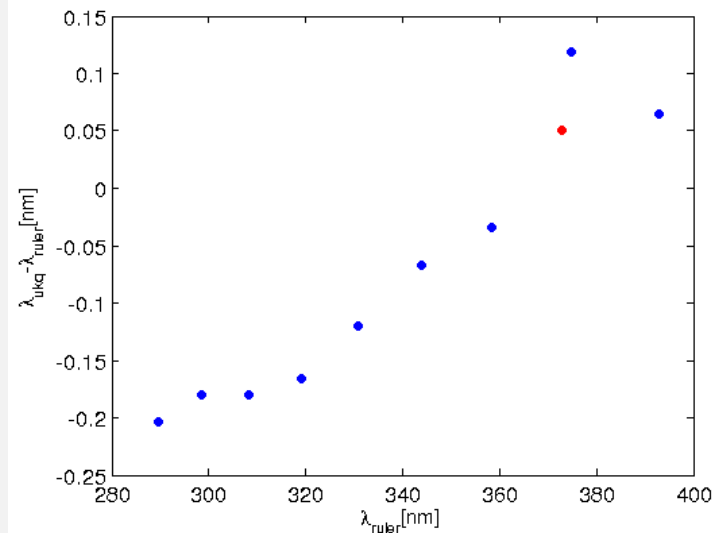
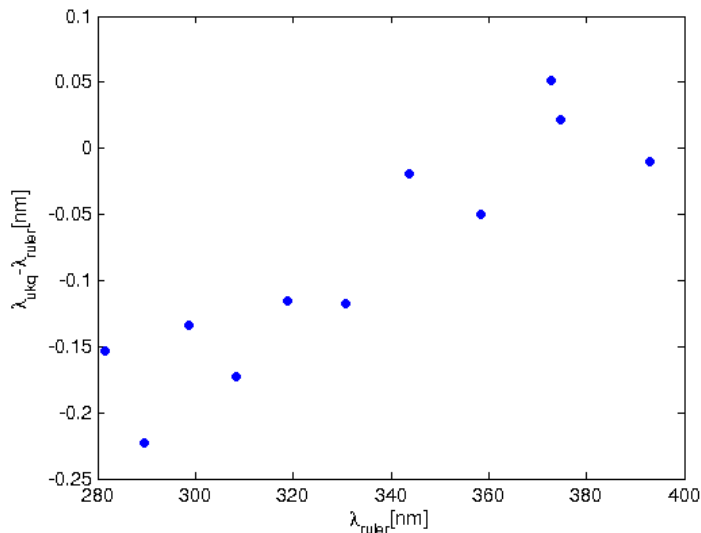
For one single device:
 $\text{SNR} = 1000$
 the uncertainty on the retrieved
 thickness is at 0.1 nm level (!)



Example UKQ



Some slight difference is obtained according to which criterion is used to determine the peaks wavelengths



Conclusions

- We have discussed the general properties of a LDLS as spectral irradiance source
- Interesting applications for UV metrology, but still some improvements is necessary, especially in the beam homogenization
- Practical use as portable transfer standard and as a tool for new wavelength calibration approaches.

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